

Appl. No. 10/580,633
Amdt. Dated January 30, 2008
Reply to Office Action of November 30, 2007

Attorney Docket No. 81872.0114
Customer No. 26021

Amendments to the Specification:

Please replace the paragraph beginning at p. 22, line 17, with the following rewritten paragraph:

[0055] The surface acoustic wave element 3 for reference also consists of, similar to the surface acoustic wave element 2 for detecting pressure, an IDT 6a 3a formed on the surface of the sensor substrate 1 and reflectors 6b 3b formed on both sides in a surface acoustic wave propagation direction of the IDT 6a 3a. The method of manufacturing is the same as that for the surface acoustic wave element 2 for detecting pressure.

Please replace the paragraph beginning at p. 22, line 24, with the following rewritten paragraph:

[0056] A junction 8 is annularly formed on the surface of the sensor substrate 1 so as to surround the surface acoustic wave element 2 for detecting pressure and the surface acoustic wave element 3 for reference. The junction 8 can be formed from the same material by the same method as those for the IDTs 2a and 6a 3a and the reflectors 2b and 6b 3b. The surface thereof is subjected to Ni plating or Au plating. For improvement adhesion strength, preferably, the film thickness of the junction 8 is formed thick.